


<b>Search Notes</b>  	<b>Application/Control No.</b>  10667368	<b>Applicant(s)/Patent Under Reexamination</b>  NOGUCHI, TAKAFUMI
	<b>Examiner</b>  Choi, Jacob Y	<b>Art Unit</b>  2885

### SEARCHED

Class	Subclass	Date	Examiner
362	2, 602, 606, 617-620, 84, 34, 166, 230, 231, 244, 293, 326, 330	10/20/2005	JC

### SEARCH NOTES

Search Notes	Date	Examiner
Class/Subclass & Text Search Conducted by Examiner (including class 359)	10/20/2005	JC
Updated Search Conducted by Examiner	8/29/2006	JC
Updated Search Conducted by Examiner	2/14/2007	JC
STIC Search was performed by M. Mims (e.g., diffracting grating range)	02/6/2007	JC
Updated Search Conducted by Examiner	8/22/2007	JC
Updated Search Conducted by Examiner	3/14/2008	JC
Updated search, Assignment data search, Inventor name search, Back/Forward search	12/10/2008	JC
Updated search	7/14/2009	JC
Updated search	11/30/2009	JC

### INTERFERENCE SEARCH

Class	Subclass	Date	Examiner
PG pub text search	See interference search printout	11/30/2009	JC

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Primary Examiner.Art Unit 2885